

## Supplementary Information

### Application of Microwave Synthesized Ultra-smooth a-C Thin Film for the Reduction of Dielectric/Semiconductor Interface Trap States of an Oxide Thin Film Transistor

Nila Pal<sup>a</sup>, Baishali Thakurta<sup>b</sup>, Rajarshi Chakraborty<sup>a</sup>, Utkarsh Pandey<sup>a</sup>, Vishwas Acharya<sup>a</sup>, Sajal Biring<sup>c</sup>, Monalisa Pal<sup>b\*</sup>, and Bhola N. Pal<sup>a,c\*</sup>

<sup>a</sup>*School of Materials Science and Technology, Indian Institute of Technology (Banaras Hindu University), Varanasi-221005, India*

<sup>b</sup>*Department of Chemistry, Banaras Hindu University, Varanasi-221005, India*

<sup>c</sup>*Organic Electronics Research Center and Department of Electronic Engineering, Ming-Chi University of Technology, New Taipei City, Taiwan 243*

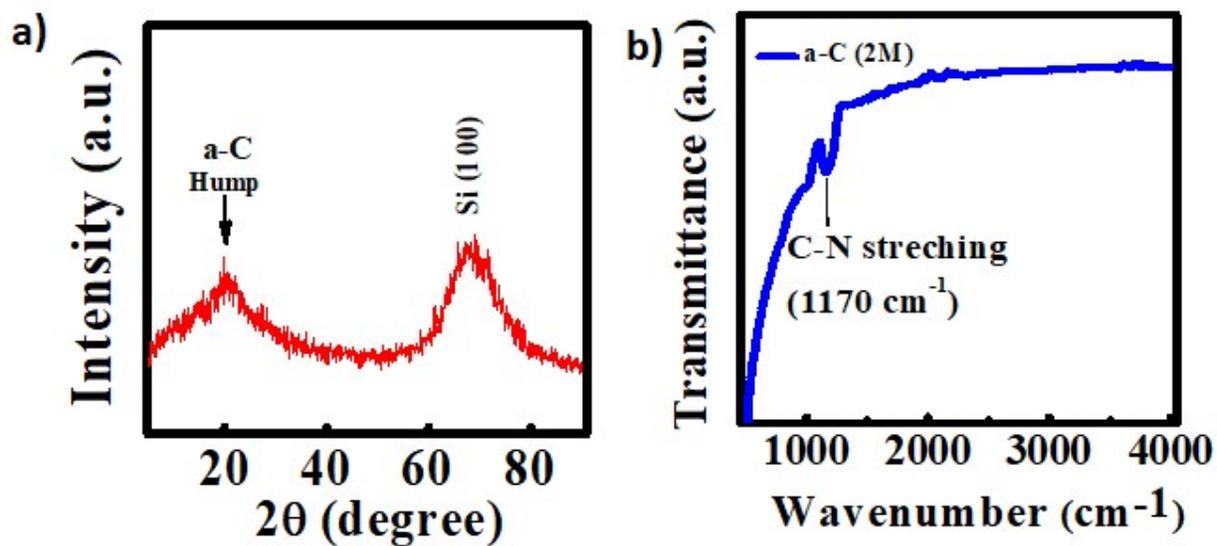
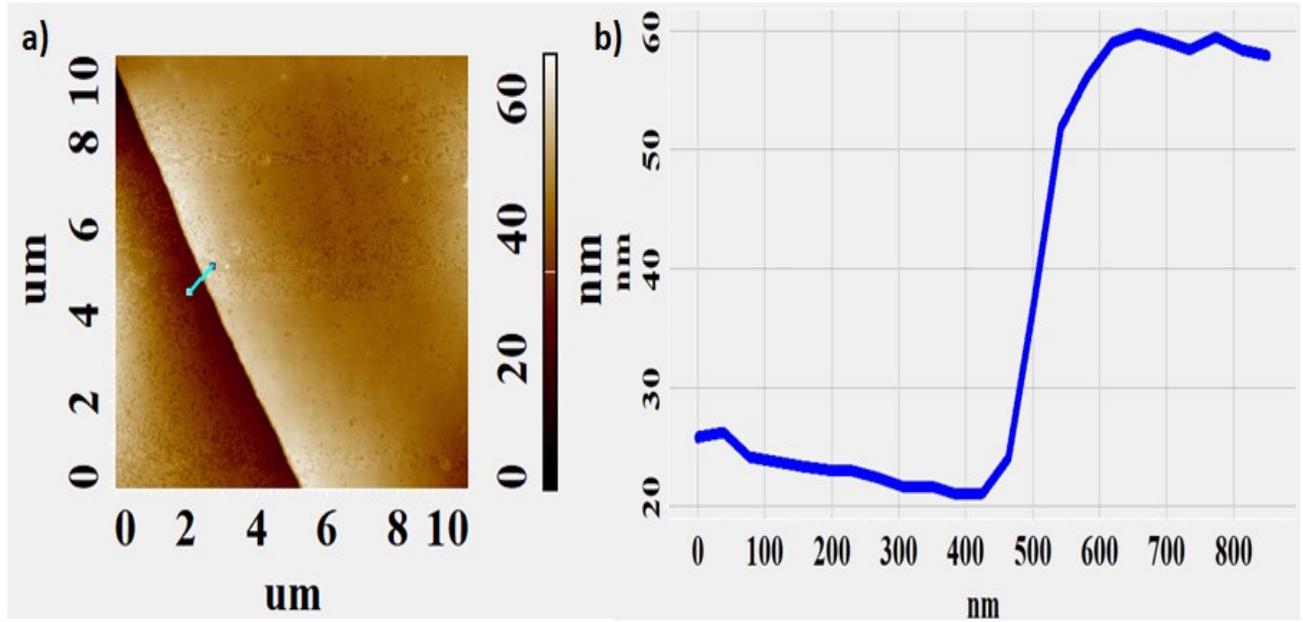
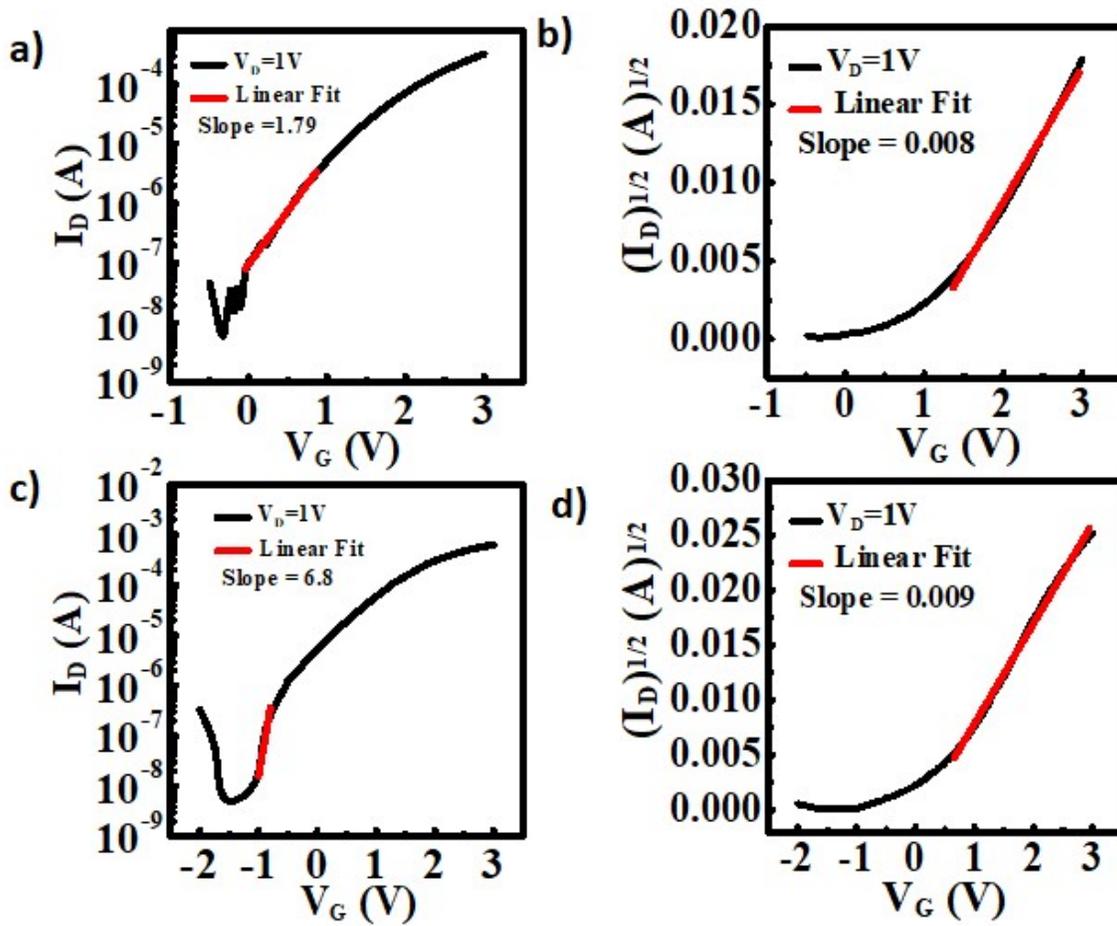


Figure S 1a) XRD pattern, b) FTIR spectra of a-C thin film on  $p^{++}$ -Si substrate.



**Figure S 2a)** AFM image, **b)** height profile of a-C thin film on p<sup>++</sup>-Si substrate



**Figure S 3** Linear fitting at lower region of  $\log(I_D)$  vs.  $V_G$  curves of a) device-1, c) device-2 for Subthreshold Swing value calculation. Linear fitting of  $(I_D)^{1/2}$  vs.  $V_G$  curve of b) device-1, and d) device-2 to extract the slope for mobility calculation.

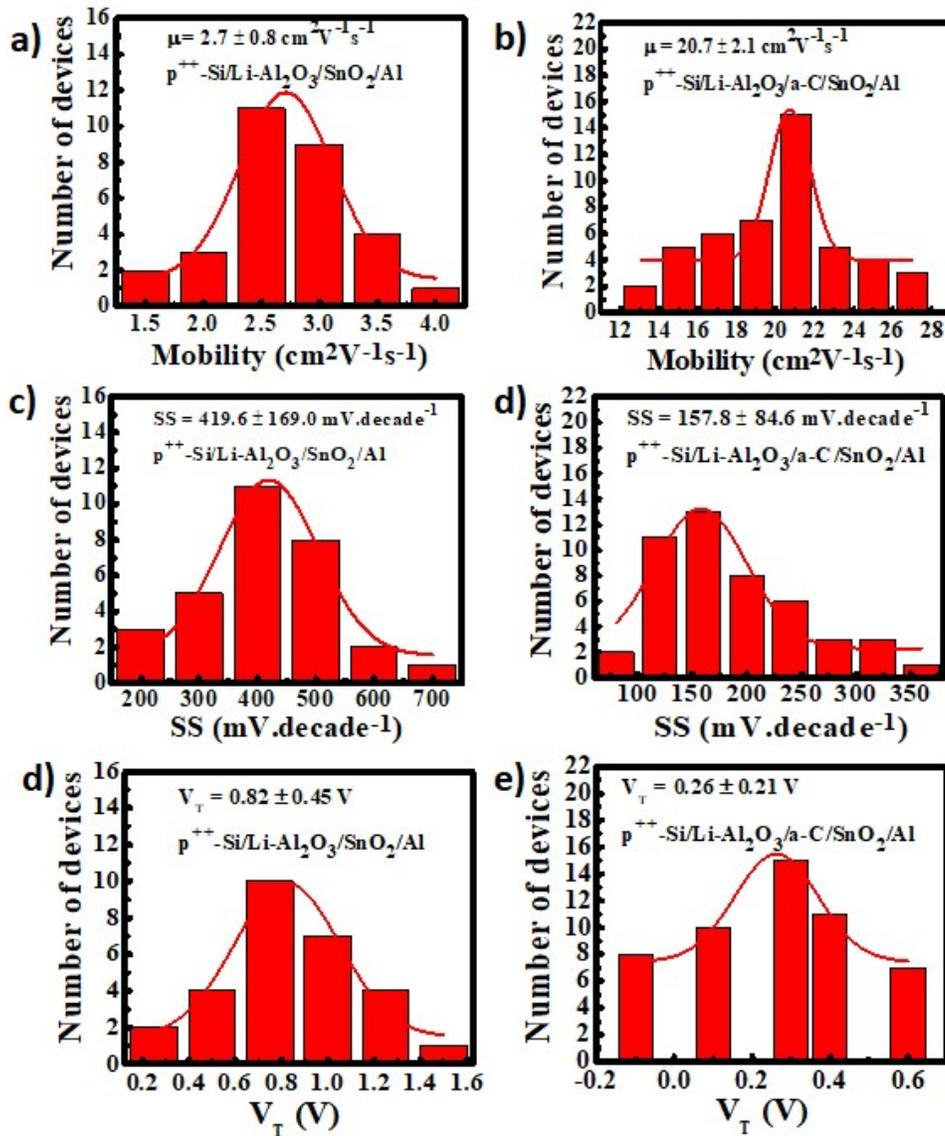


Figure S 4 Histogram of Li-Al<sub>2</sub>O<sub>3</sub> gate dielectric (w and w/o a-C interface) TFT a) number of devices tested with mobility for device-1 b) number of devices tested with mobility for device-2 c) number of devices tested vs. SS value of the device-1 d) number of devices tested vs. SS value of the device-2 e) number of devices tested vs. V<sub>T</sub> of the device-1 f) number of devices tested vs. V<sub>T</sub> of the device-2

**Table S1:** Statistical values of device parameters

<b>Device</b>	<b>Threshold Voltage (V)</b>	<b>Subthreshold Swing (mV.decade<sup>-1</sup>)</b>	<b>Saturation Mobility (cm<sup>2</sup>.V<sup>-1</sup>.s<sup>-1</sup>)</b>
p <sup>++</sup> -Si/Li-Al <sub>2</sub> O <sub>3</sub> /SnO <sub>2</sub> /Al	0.82 ± 0.45	419.6 ± 169.0	2.7 ± 0.8
p <sup>++</sup> -Si/ Li-Al <sub>2</sub> O <sub>3</sub> /a-C/SnO <sub>2</sub> /Al	0.26 ± 0.21	157.8 ± 84.6	20.7 ± 2.1